



IBM GES

Modeling MOSFET Process Variation using PSP

Josef Watts, Yoo-mi Lee, Jae-Eun Park

What this talk is about:

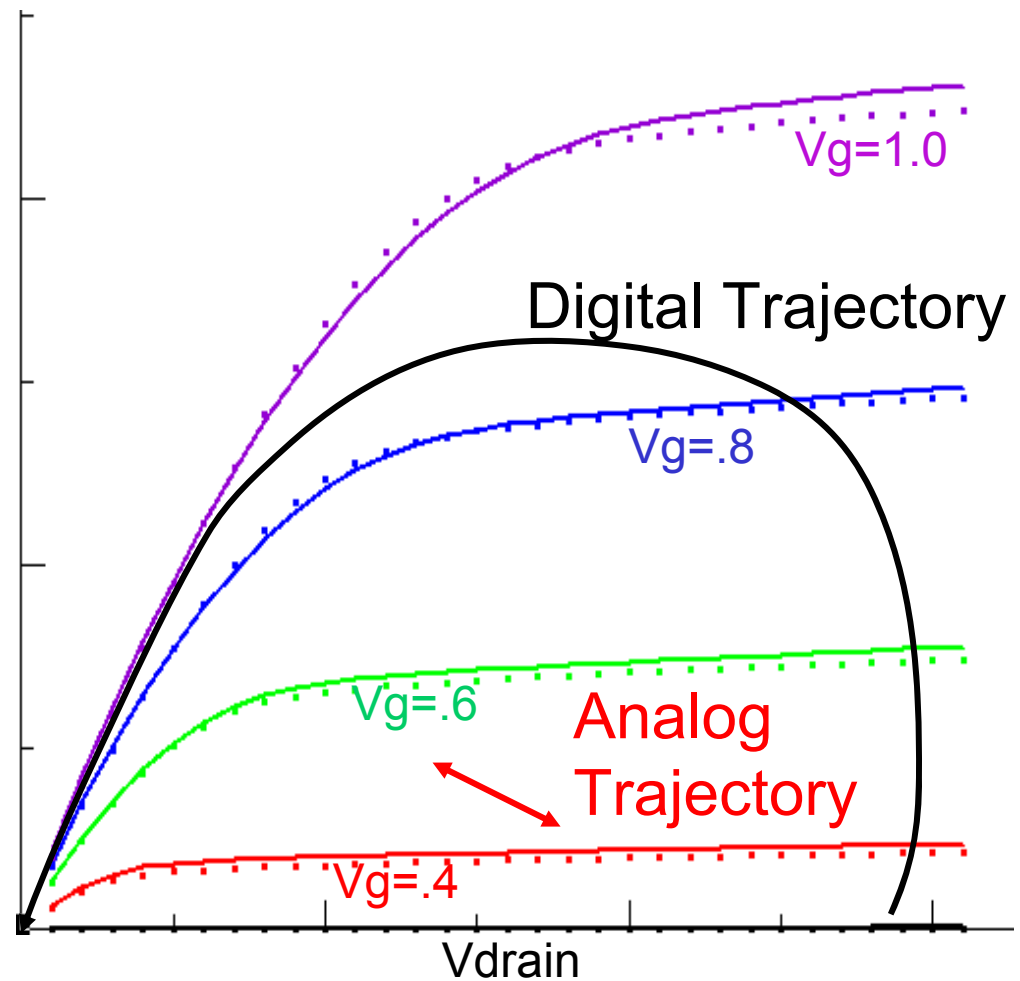
- **How to setup a production methodology to model chip mean variation of MOSFET channel current**
 - For designers of any style circuit for any application
 - For high volume production modeling
 - Using the PSP Global Parameter Set
 - PSP is the next generation MOSFET model select by the CMC

Approaches to model variation

- **Fixed corners**
 - Different parameter sets for Fast, Slow, High leakage, NFET fast – PFET Slow, etc.
- **Skewing parameter aka user defined corners**
- **Monte Carlo**
- **We believe you a good Monte Carlo model to develop the others**

Circuit Designer Requirement for the Process Model

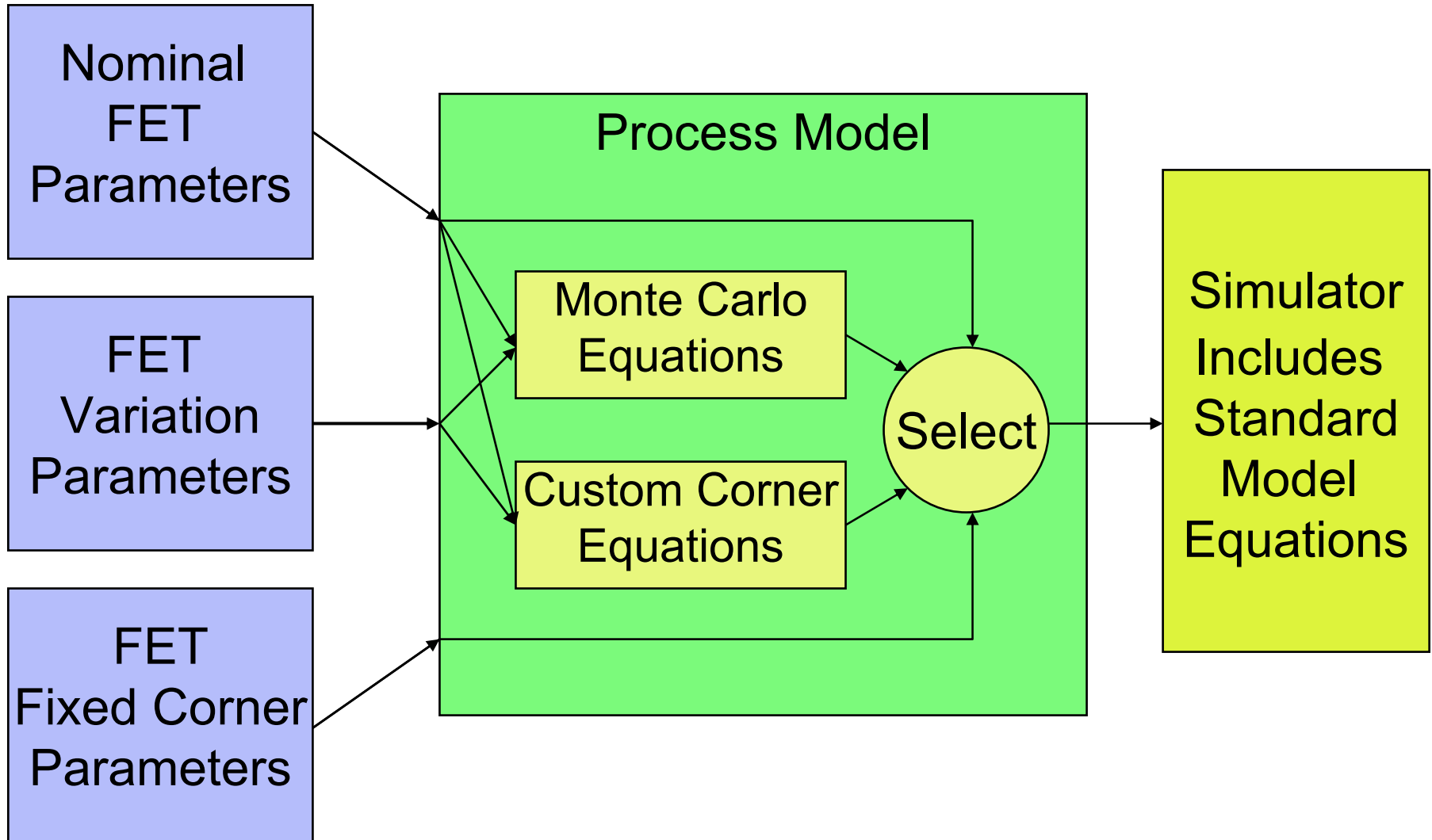
- Predict range of circuit performance by
 - V_t
 - I_d
 - G_m
 - etc.
- covering the full range of device performance
- Capture the relationships between characteristics



Modelers Requirement for the Process Model

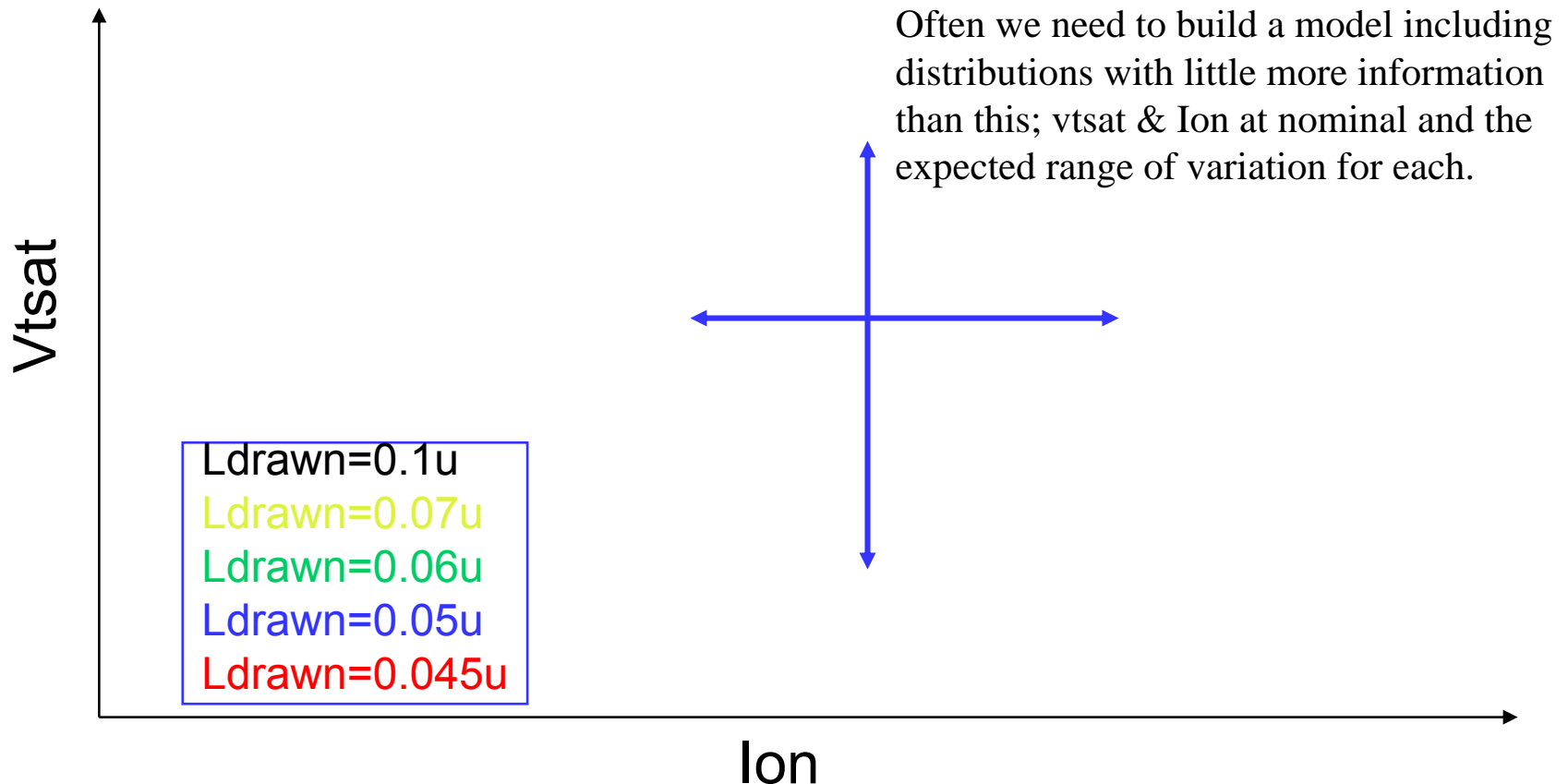
- **Standard form for**
 - Rapid Development Testing & Deployment
 - Model build using limited data
- **Model parameters to varied which capture physical correlations (even when you don't have data)**
- **Model parameters are robust i.e. effective for various device types and model fits**

Standard Form: Anatomy of an FET compact model



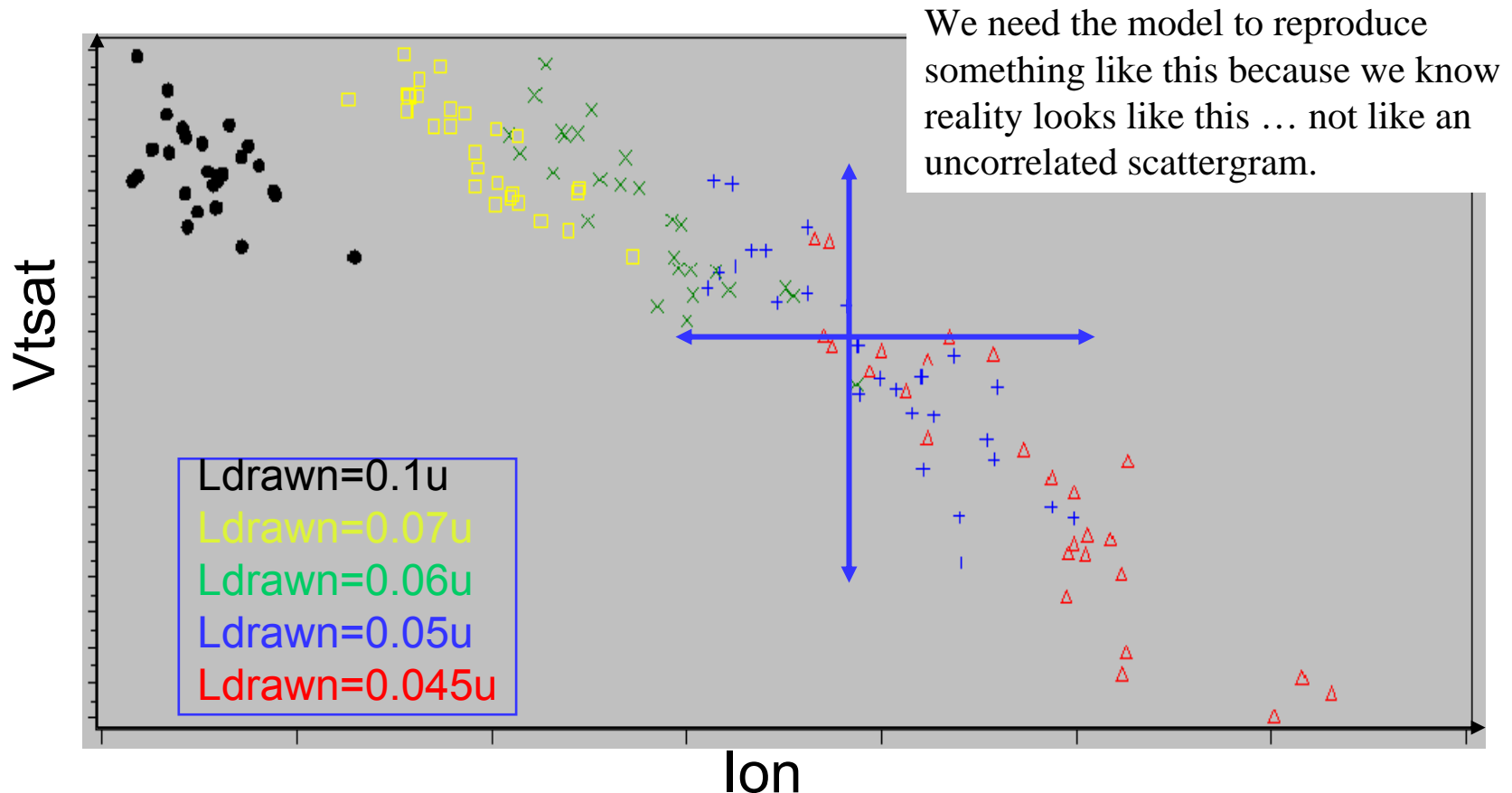
Modelers Requirement for the Process Model

- **Build the process model from limited or imaginary data**
- **Capture the relationships between characteristics**



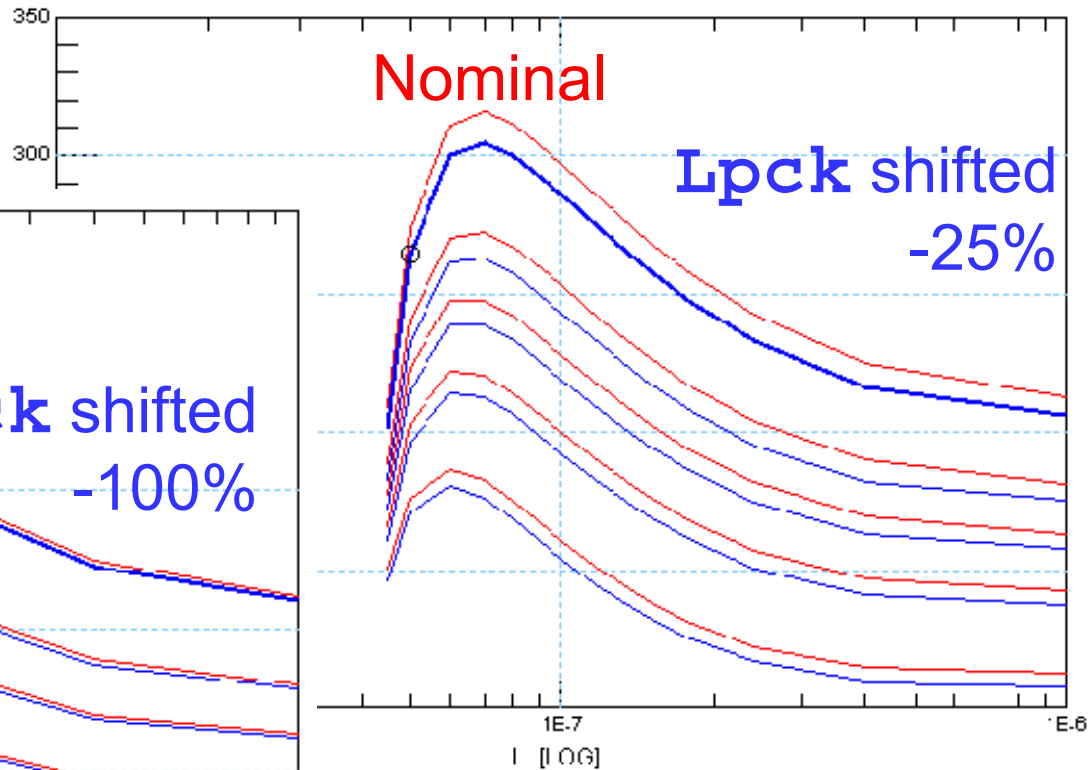
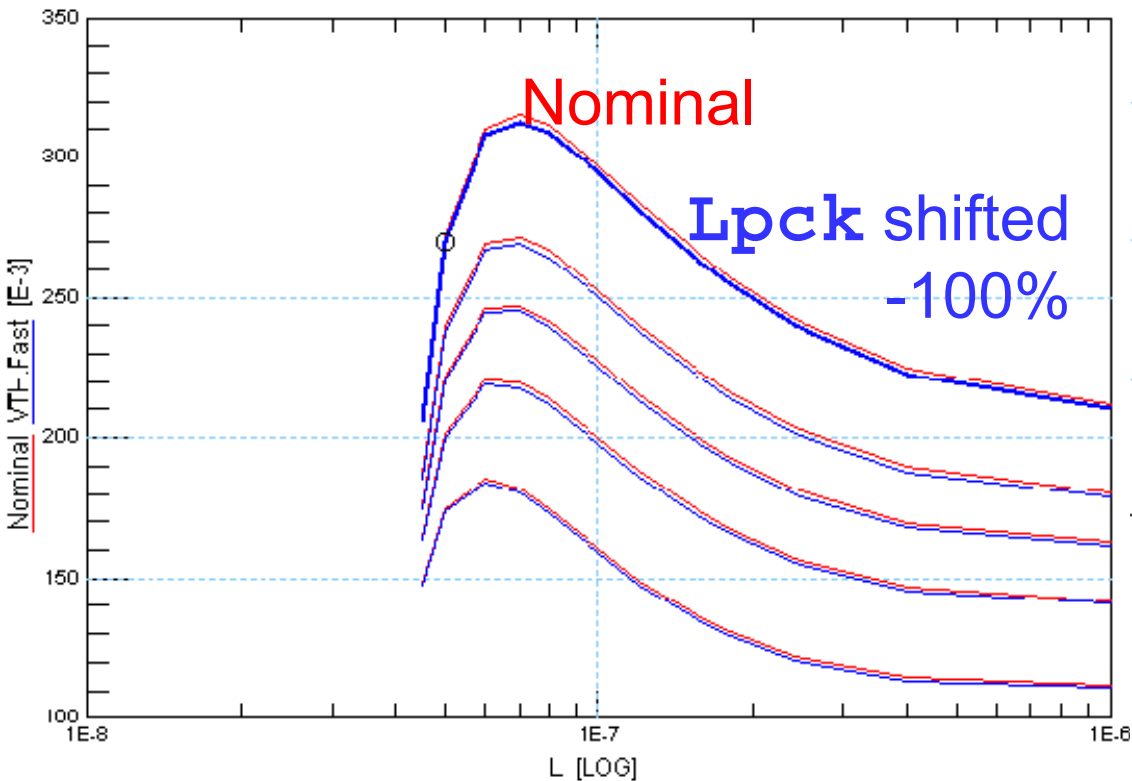
Modelers Requirement for the Process Model

- Build the process model from limited or imaginary data
- Capture the relationships between characteristics



Model Parameters used are robust

Parameter L_{pck} is not robust. If set too small in fitting it has no effect.



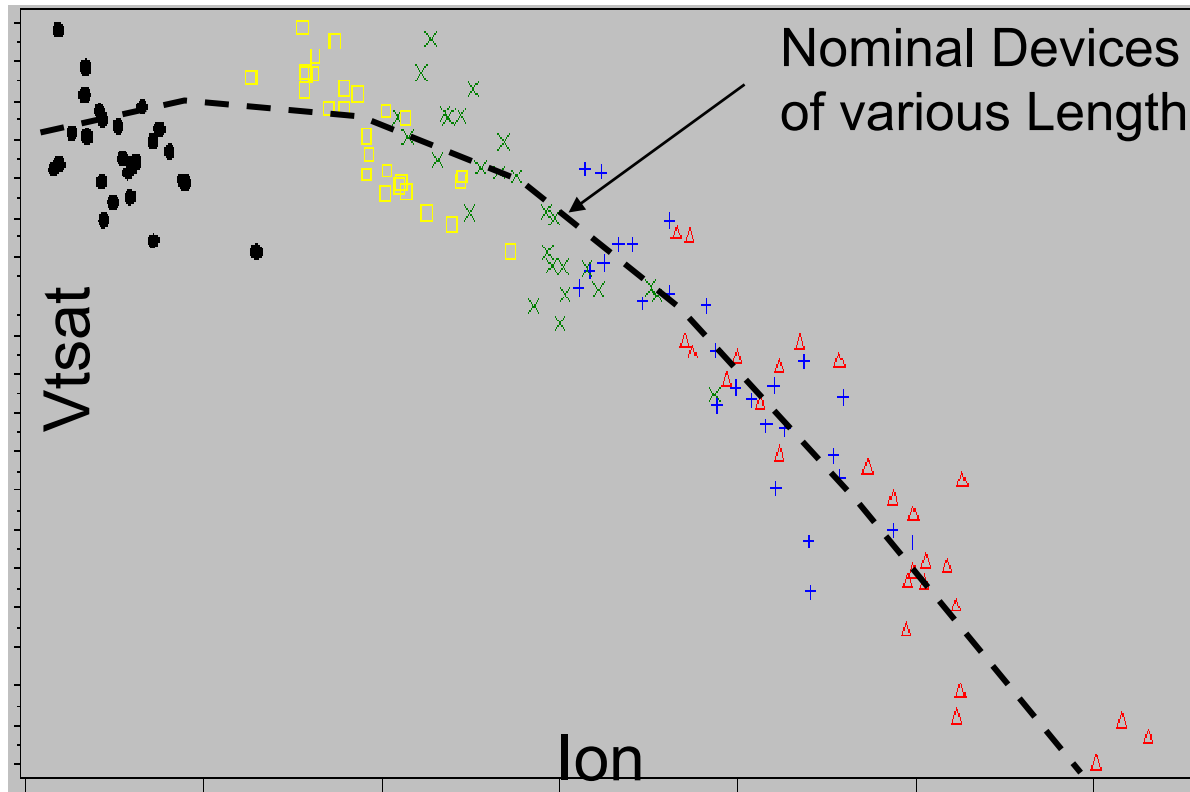
Two fittings of V_t vs. L

How to start?

- **Choose a technology where you have real variation data from running the line over time.**
 - I have a 65nm NFET/PFET pair
 - A dozen wafers from a dozen lots over a year's production
- **Measure detailed data from multiple chips**
 - Full I_dV_g and I_dV_d sweeps at multiple V_{body} steps
- **Examine the data for independent modes of variation**
- **Look for Robust parameters to model the modes**
 - Ideal parameters are measurable independently

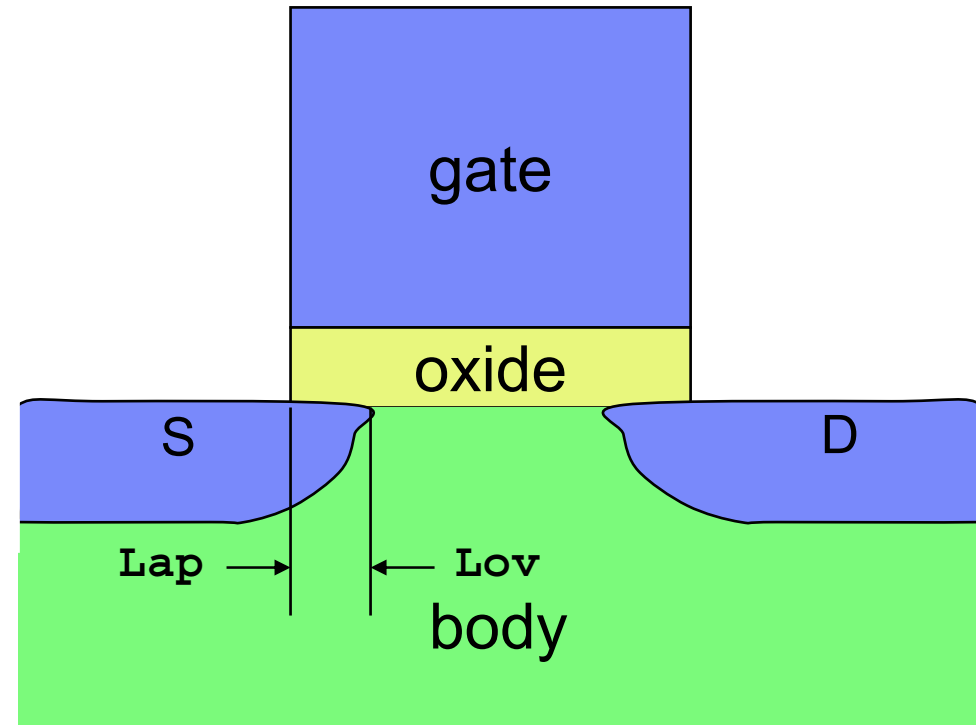
Length and Width

- LVARO, WVARO
- **Good measurements taken inline, can set independent of electrical data**
- **Strong effect regardless of fit**
- **Physically capture I_d , V_t , etc.**



Lap and Lov

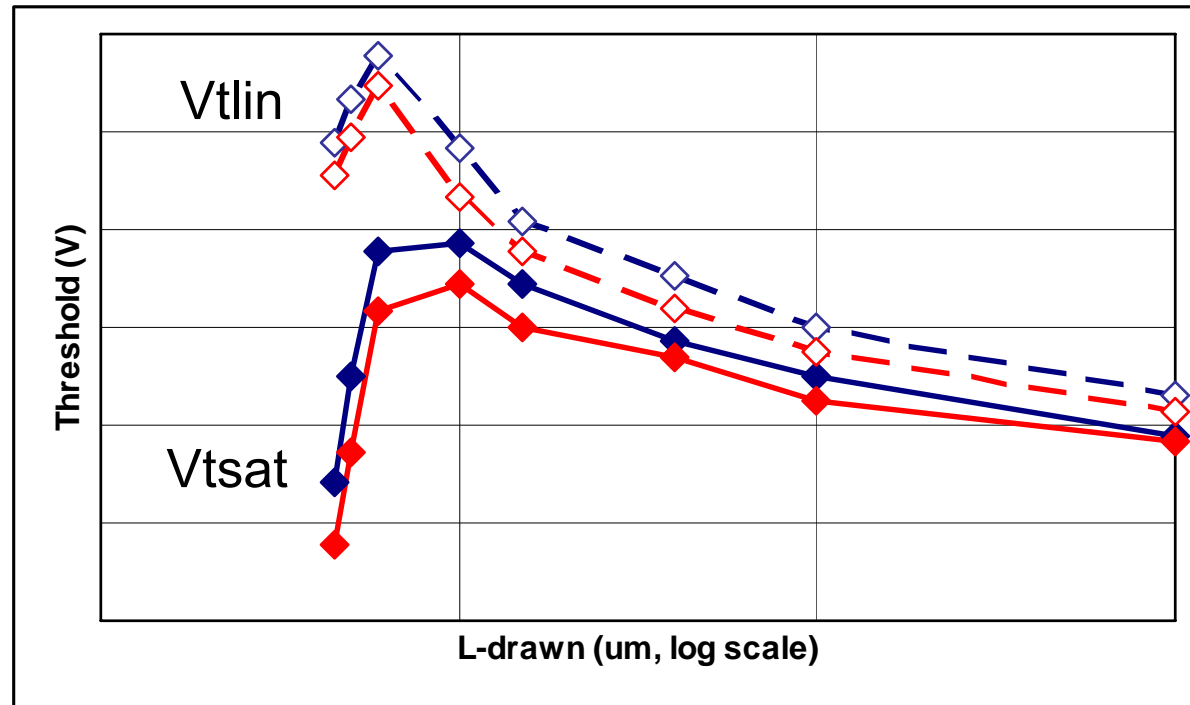
- L_{ap} and L_{ov} represent the same physical distance for IV and CV respectively
- C_{ov} and L-dependent quantities like I_{on} are correlated even if your data doesn't show it
- $\Delta L_{ap} = \Delta L_{ov} * m_{cov}$



Variation in the V_t vs. L curve

- Overall shift

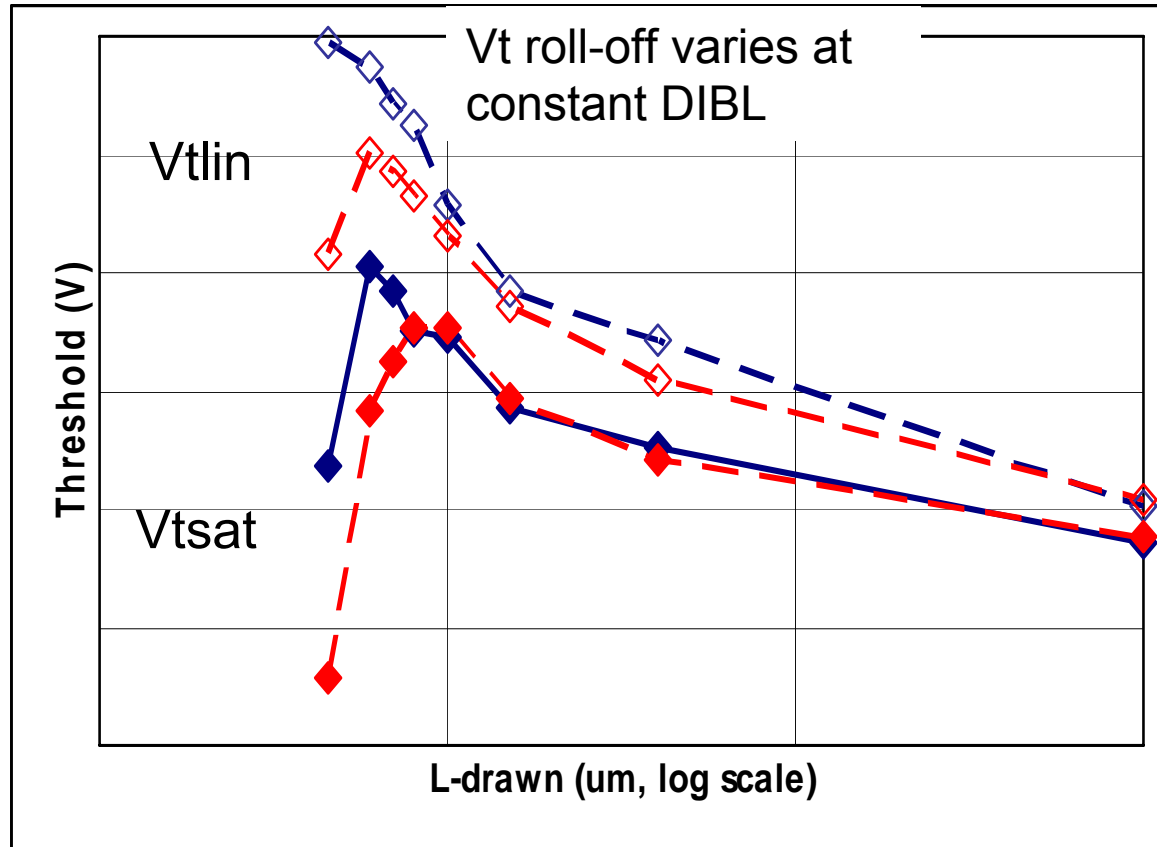
- N_{sub}
- Moves overall V_t
- Moves body effect
- Very robust



Blue and Red represent measured data from different chips

Variation in the V_t vs. L curve

- **Short channel variation**
 - Constant long channel V_T
 - Constant DIBL
 - Variation in Roll-off
 - Also see variation in DIBL but ΔL variation model this



Blue and Red represent measured data from different chips

Possible PSP parameters for V_t variation of short FETs

$$\mathbf{NSUB} = f(N_{\text{subO,eff}}, N_{\text{pck,eff}}, L_{\text{pck,eff}})$$

where f is an increasing function of all arguments and

$$N_{\text{pck,eff}} = \mathbf{NPCK} \cdot \text{MAX} \left(\left[1 + \right. \right.$$

$$L_{\text{pck,eff}} = \mathbf{LPCK} \cdot \text{MAX} \left(\left[1 + \right. \right.$$

Narrow W terms

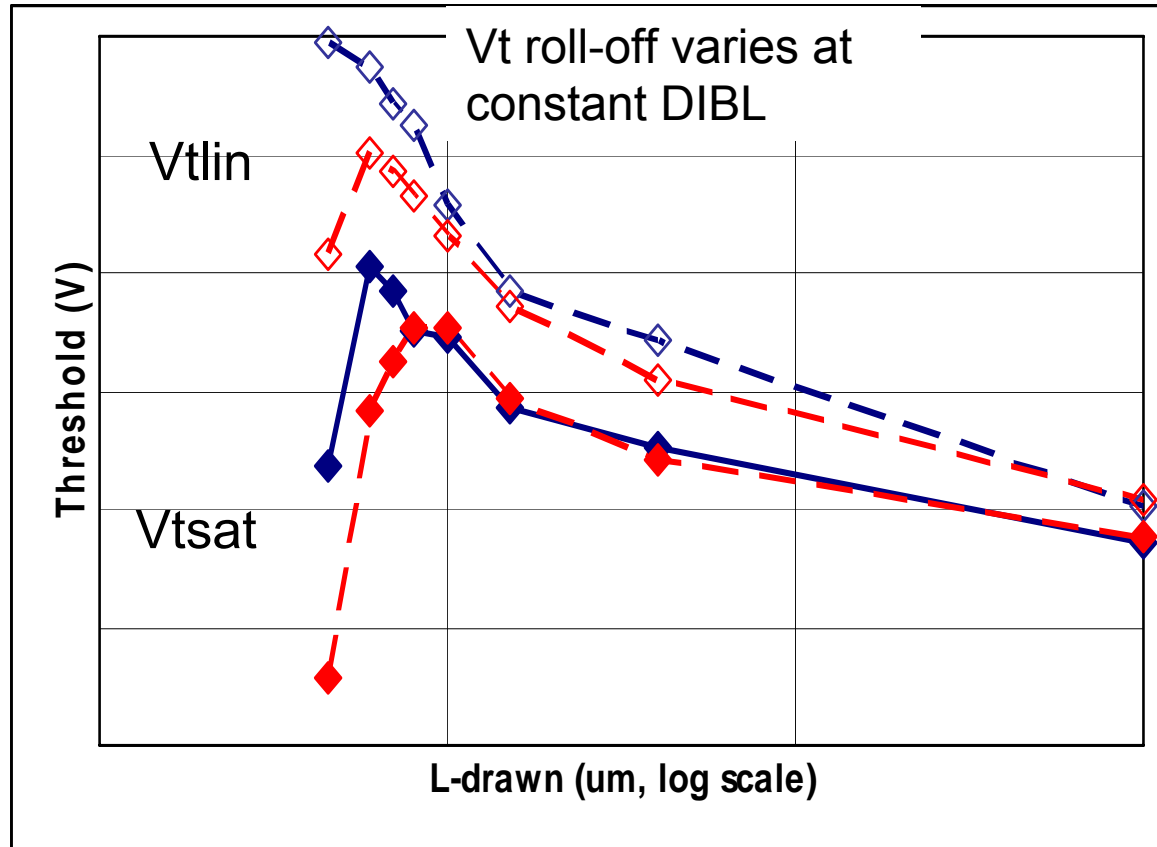
$$\mathbf{NEFF} = N_{\text{sub}} \cdot \left(1 - \mathbf{FOL1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} - \mathbf{FOL2} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^2 \right)$$

- **NSUBO** effects all lengths
- **NPCK**, **LPCK** model halo doping
- **FOL1**, **FOL2** are short channel fitting terms
- **VFBL** is a short channel adjustment to flatband

Variation in the V_t vs. L curve

- **Short channel variation**

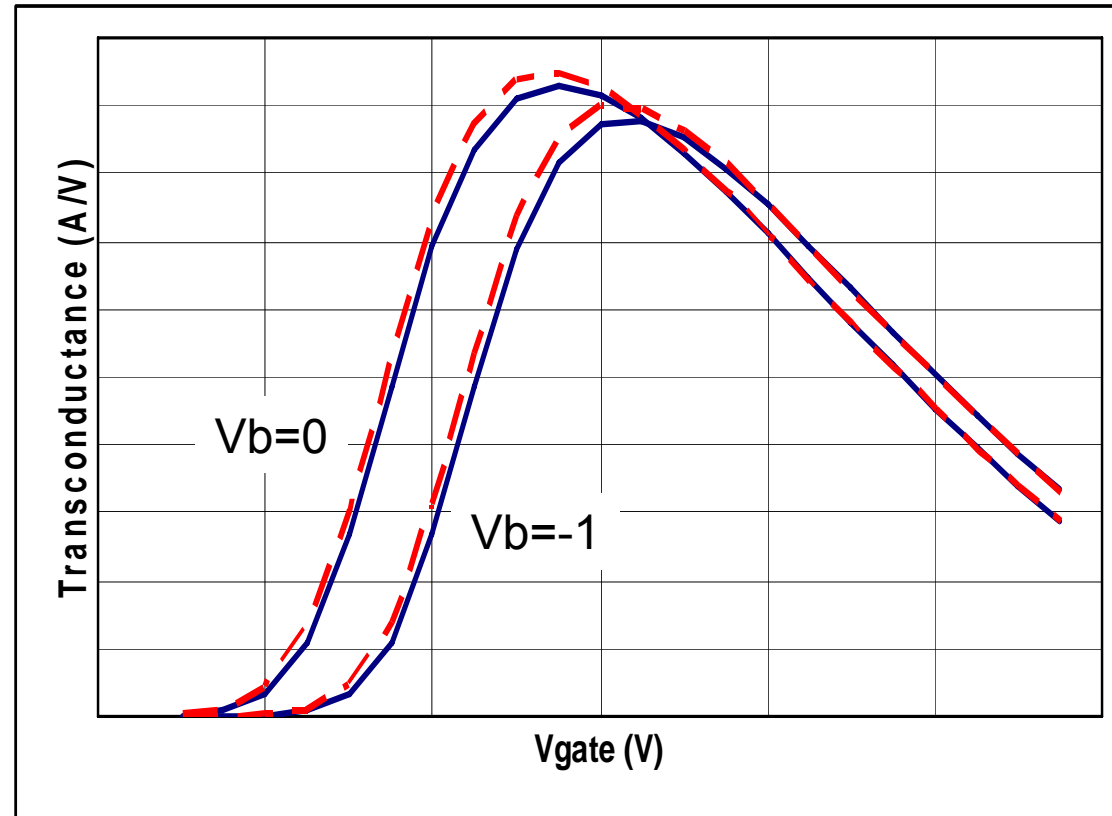
- ✗ N_{pck} (pocket doping parameter) too strong for long devices + not appropriate for no-halo FETs
- ✗ F_{o11} or F_{o12} (Short Channel Effect parameters) not robust to fitting.
- ✗ V_{FBL} not as strongly short channel, does not change body effect
- ✓ F_{o11} and F_{o12} by the same fraction



Blue and Red represent measured data from different chips

Transconductance, long L

- **Variation in peak gm of long devices with similar V_t**
 - Small effect
 - Model with μ_0 (base mobility)
 - Other features of gm curves are quite constant



Blue and Red represent measured data from different chips

Transconductance: Short L

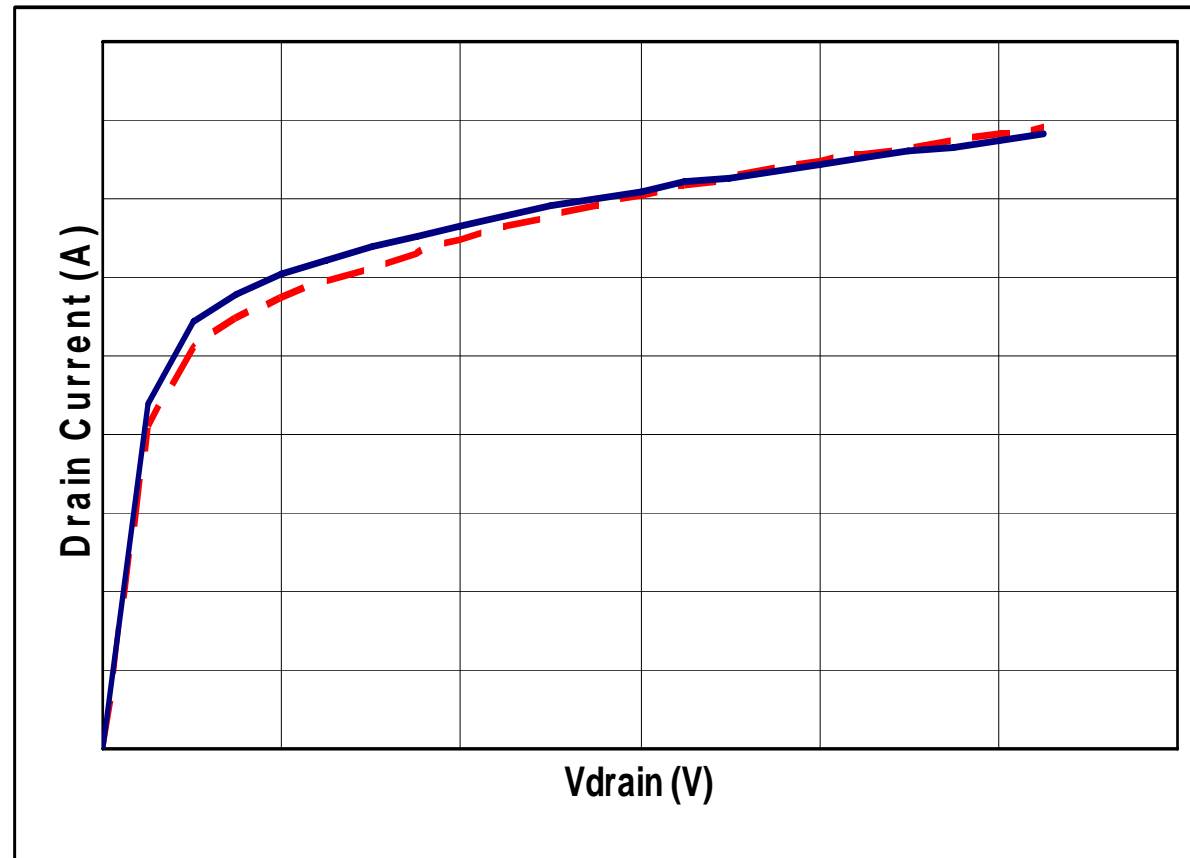
- **Variation in peak gm of short devices**
 - Short channel mobility?
 - Series resistance?
 - Constant fraction at all V_g suggests R
 - R_{sw1} is more robust than the available mobility scaling parameters

gm variation (1 sigma)		
Ldrawn	Peak gm	Gm at $V_g=1.1*V_{dd}$
1.0um	1.0%	0.6%
0.05um	3.6%	3.7%

Output Conductance

- g_{ds} varies with V_t and u_0 but $I_d V_d$ curves will not cross
- A_{lp1} is robust and has the proper behavior over length

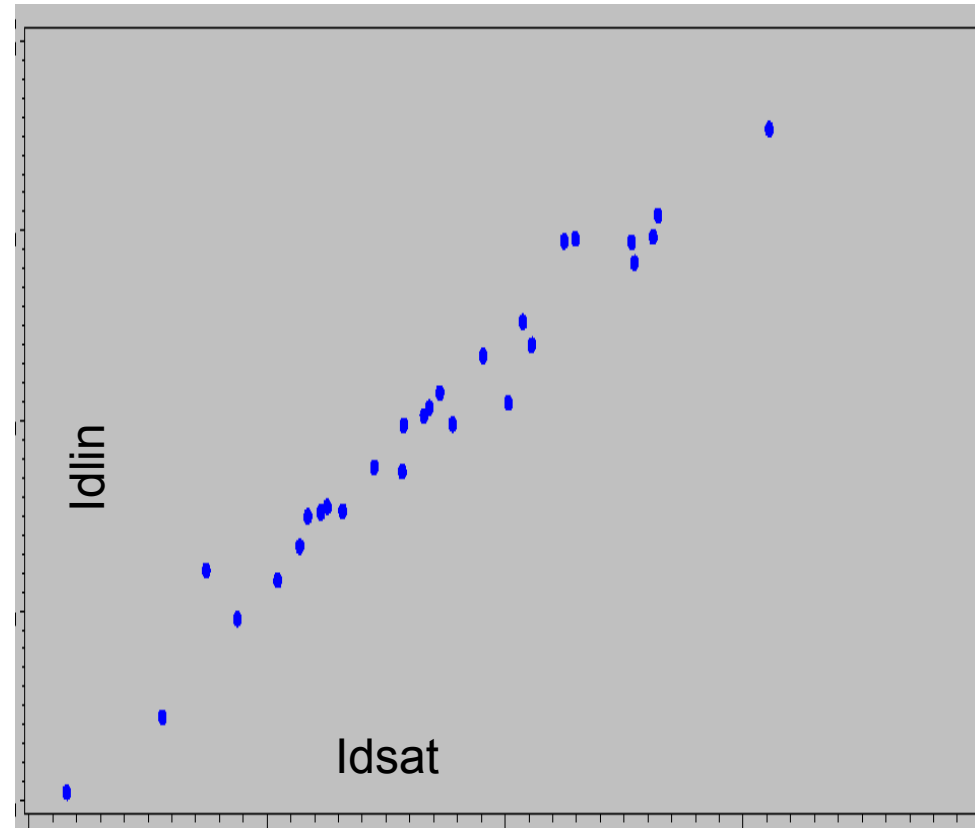
Long channel $I_d V_d$



Blue and Red represent measured data from different chips

Things that we didn't need

- **Short channel linear vs. saturated current**
 - $I(V_d=.05)$ vs. $I(V_d=1.0)$
 - $R^2 = .98$ NFET; $.92$ PFET
- **Addition Narrow Effects**
 - Have variation of delta W
 - Have random dopant fluctuations



Summary

- **Modeling Process Variation in a Production Environment requires**
 - A predefined process model
 - Parameters which describe independent physical sources of variation
 - Parameters which are robust in the sense that they are effective for various device design and various examples of poor fitting.